

Wavefront sensor based on modified Talbot effect

M. Bichra, N. Sabitov, S. Sinzinger
 Fachgebiet Technische Optik, Technische Universität Ilmenau



Introduction

Wavefront measurements are important in many fields of applied optics such as wavefront control of laser beams, optical diagnostics of the surface, human-eye aberration measurements, etc. The sensor, based on the Talbot effect, can be a good alternative to the Shack–Hartmann sensor. A modified method of shearing grating interferometry is presented. This novel method allows measuring of freeform wavefronts with high accuracy. The experimental results are obtained using a binary amplitude grating and a spatial filter for the zero order. The filtering of the zero diffraction order results in an improved contrast and measurement performance. By means of robust and fast software, we are able to precisely reconstruct the wavefront. A comparison of this method with Shack Hartmann Sensor (SHS) is presented.

1 Standard wavefront measurement method

Shack Hartmann principle

Challenges:
 Lateral resolution
 not suitable for wavefront with high inclination
 Limited dynamic range

Interferometry and null test

Challenges:
 High alignment
 Need of a null element
 High cost

2 Talbot wavefront sensor

Main setup

Algorithm

According to Takeda theory, the subspectra of the Talbot plane intensity provide all information about the wavefront. If the subspectra are filtered and moved to the center, the x,y gradient maps of the wavefront before the grating can be measured.

Simulation

To show the limitation of the standard Talbot wavefront sensor, reconstruction of a random signal is simulated. After the grating, the subspectra of the Talbot plane interfere and make the filtering of the right subspectra difficult. Since the reconstruction of the wavefront based on gradient integration always includes errors, we will compare in this simulation only the signal gradient maps and their reconstruction. The integration error is then eliminated.

Challenges:
 If the signal is complex, the subspectra of the intensity are mixed. The filtering of the suitable subspectrum is not possible

4 Experiment

Freeform

Material: PMMA, Thickness 7 mm
 Sag: 0.7798mm, 7th Order Polynomial

$$z = \frac{cr^2}{1 + \sqrt{1 - (1+k)c^2r^2}} + \sum_{i=1}^N A_i E_i(x,y)$$

Grating
 Period = 50µm

Filter

CMOS Uyei Camera
 Resolution: 1280x1024
 Pixel size: 5,3µm

Setup

Achromat1, f' = 40mm Achromat2 f' = 60mm

Intensity on the Camera Plane: (a) Without, (b) with Filtering

SHS measurement **Modified Talbot wavefront sensor** **Point by point difference**

3 Modified Talbot sensor

The idea is to image the Talbot-Plane into the Camera Plane with a 4 f System. The +1 and -1 orders in x and y direction in the Fourier plane of the first Lens are filtered. With such filtering, we are able to select the intensity of the subspectra on the camera plane without losing any information.

Idea

Simulation

Spectrum of the intensity on the camera plane:
 (a) with filtering,
 (b) without filtering

Algorithm

Conclusion

We have presented a method of wavefront measurement by modified digital Talbot interferometry. The experimental results were found to be in good agreement with the result obtained by ray trace calculation in Zeemax. The technique enables a fast measurement of the wavefront with improved accuracy and sensitivity compared to conventional Talbot interferometry. A comparison of this method with Shack Hartmann sensor was presented.

Literature

- [1] S. Sinzinger, M. Hillenbrand, R. Hasan Abd-El Maksoud, "Freeform Surfaces in Optical (Micro-) systems: From Parabol Theory to Applications", OSA Topical Meeting on Freeform Optics, Tucson, Az. USA, 3.-7.11.2013.
- [2] G. S. Khan, M. Bichra, A. Grewe, N. Sabitov, K. Mantel, I. Harder, A. Berger, N. Lindlein, S. Sinzinger, "Metrology of freeform optics using diffractive null elements in Shack-Hartmann sensors", EOSMOC 2013: 3rd EOS Conference on Manufacturing of Optical Components, Munich, 12.5.-16.5.2013.
- [3] H. Schreiber, J. Schwider "Lateral shearing interferometer based on two Ronchi phase gratings in series" APPLIED OPTICS y Vol. 36, No. 22 y 1 August 1997

Acknowledgements

This work has been funded by the Carl Zeiss Stiftung through the project "System for Automated Cell Cultivation and Analysis (SACCA)" and the German Research Foundation DFG through the project "Adaptive Scanning Single-Facet Eye" (SI 573/7-2) within the Priority Program SPP 1337 "Active Micro-optics."



Fakultät für Maschinenbau
 IMN MacroNano
 Fachgebiet Technische Optik
 Mohamed Bichra

Telefon +49 3677 69-1806
 Fax +49 3677 69-1281
 mohamed.bichra@tu-ilmenau.de
 www.tu-ilmenau.de/optik

